

MC-PAD Closing Network Event

Project 2: Hybrid Pixel Detectors

*(X-ray Radiation Damage Studies and Design of
a Silicon Pixel Sensor for Science at the XFEL)*

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Outline

Scientific work:

- Motivation: Radiation hard silicon sensors for the XFEL
- Selected topics in this talk:
 - Understanding of X-ray induced radiation damage
 - Characterization and determination of damage related parameters
 - Influence on electric properties of segmented sensors
- Review on other achievements

General aspects:

- Benefits from MC-PAD framework
- Suggestions

Motivation

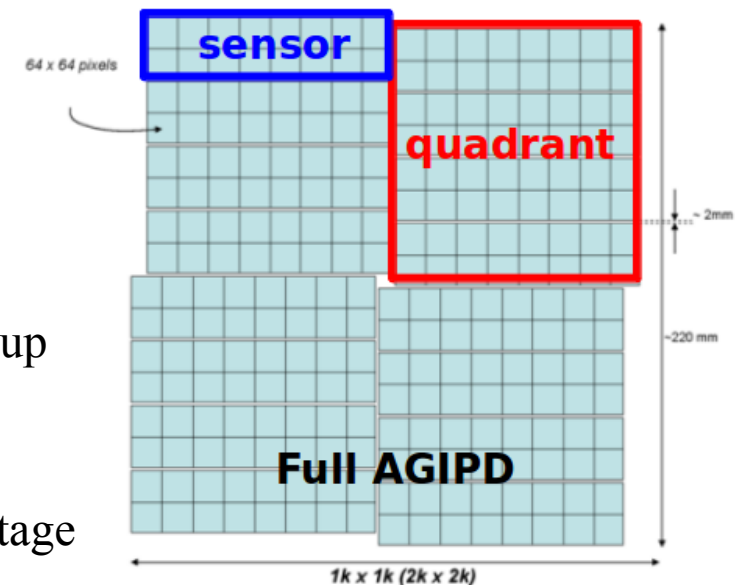
Motivation: Development of radiation hard (**0 - 1 G Gy!**) silicon pixel sensors for experiments with hard X-rays (3 keV – 25 keV) at the European XFEL - work done within AGIPD collaboration

Method (collaboration with J. Schwandt, PhD student, Hamburg University):

- Extract microscopic parameters related to X-ray irradiation
- Understand the influence of X-ray irradiation on electrical properties of segmented sensors
- Implement the extracted parameters in TCAD simulation and verify results with measurements on segmented sensors
- Optimize sensor design using TCAD simulation
- Sensor layout design based on optimized parameters

Main effects in silicon sensors @ XFEL:

- No bulk damage for $E_{x\text{-rays}} < 300 \text{ keV}$
- Surface damage: **oxide charges** and **interface traps** build up
 - increase leakage current (noise + power dissipation)
 - reduce breakdown voltage
 - increase inter-pixel capacitance and full depletion voltage
 - charge losses below the Si-SiO₂ interface

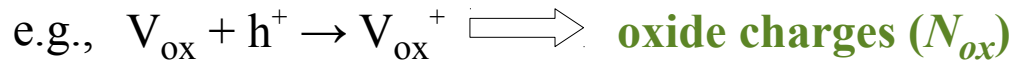


X-ray induced defects in silicon sensors

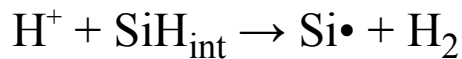
Formation of defects induced by X-ray ionizing radiation:

- X-rays produce electron-hole pairs in SiO₂ [~ 18 eV/pair]
- Fraction of electron-hole pairs recombine:
→ field dependent yield of e-h pairs
- Remaining electrons escape from SiO₂ [$\mu_e \sim 20$ cm²/(V·s)]
- Holes trapped in vacancies near Si-SiO₂ interface

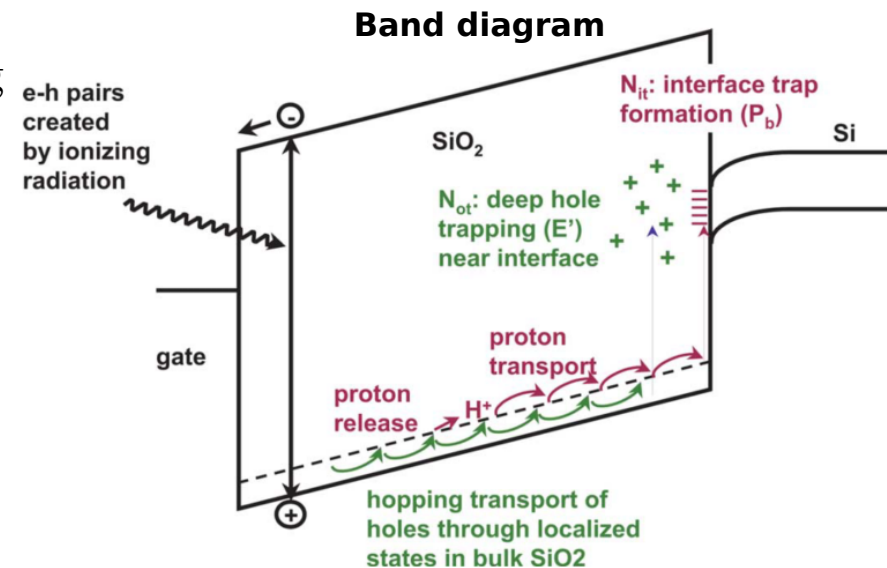
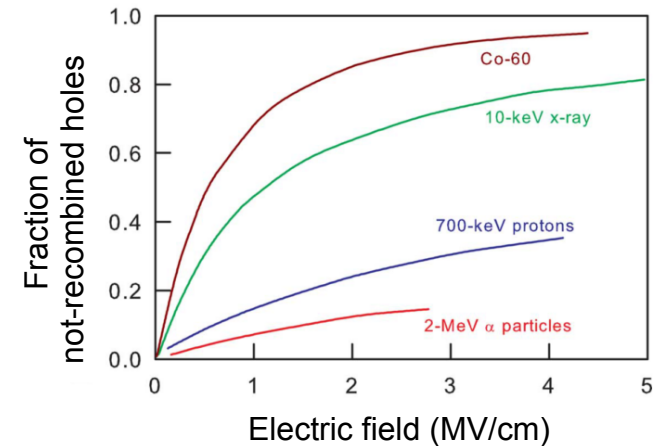
$$[\mu_h < 10^{-5} \text{ cm}^2/(\text{V}\cdot\text{s})]$$



- Protons get released and react with passivated dangling bonds at the interface:



interface traps (N_{it})

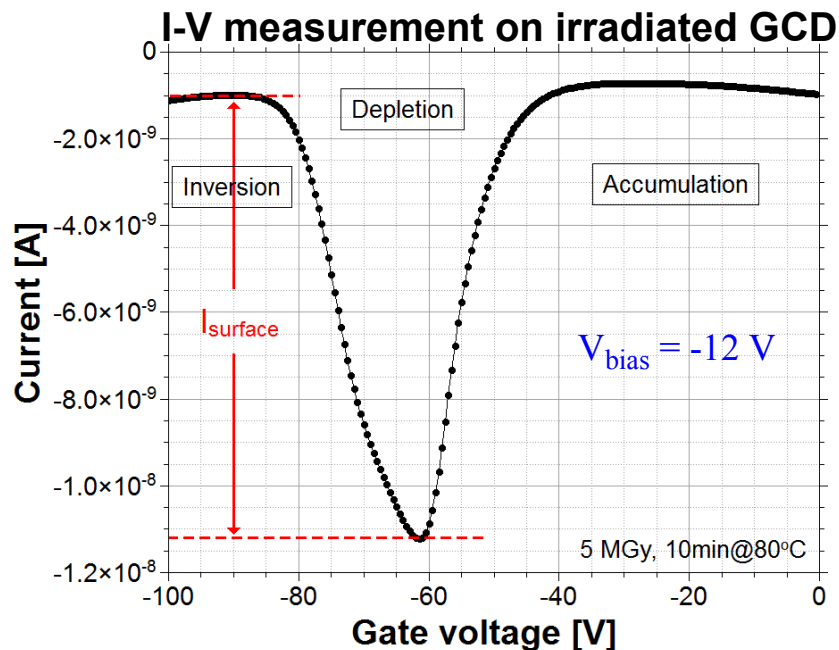
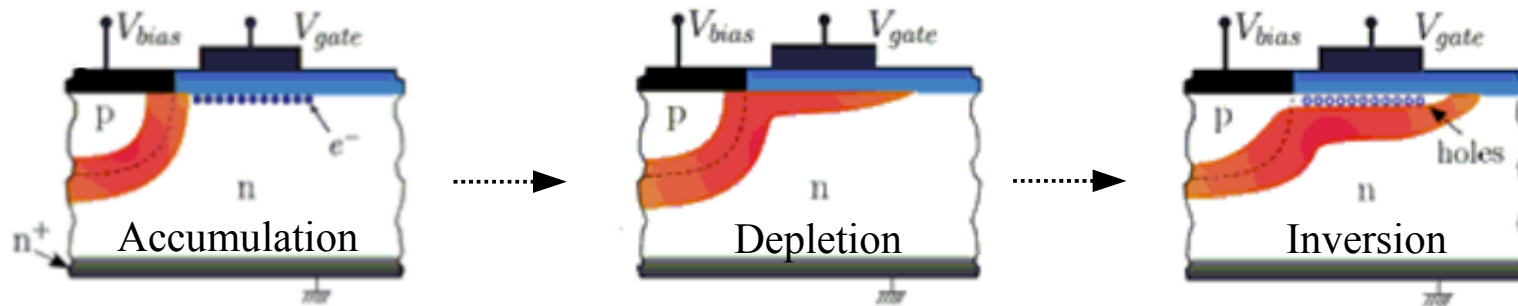


* from J.R. Schwank, 2008

Defect characterization: I-V, TDRC & C/G-V

Current-Voltage (I-V) measurement on Gate-Controlled Diode (GCD) for J_{surf} ($\mu\text{A}/\text{cm}^2$):

- Increase of surface current density $J_{surf} \leftarrow D_{it}^{mid-gap}$ ($\text{eV}^{-1}\text{cm}^{-2}$)



Accumulation: $I_{bulk,diode} + I_{diff}$

Depletion: $I_{bulk,diode} + I_{diff} + I_{surface} + I_{bulk,gate}$

Inversion: $I_{bulk,diode} + I_{diff} + I_{bulk,gate}$

$\rightarrow I_{surface} = |I_{depletion} - I_{inversion}|$

$\rightarrow J_{surf} = I_{surface}/A_{gate}$

Defect characterization: I-V, TDRC & C/G-V

Thermal Dielectric Relaxation Current (TDRC) measurement on MOS capacitor for $N_{it}^{(i)}$ (cm^{-2}):

- Measurement technique: Thermal Dielectric Relaxation Current (TDRC)

(1) Bias the MOS capacitor to accumulation

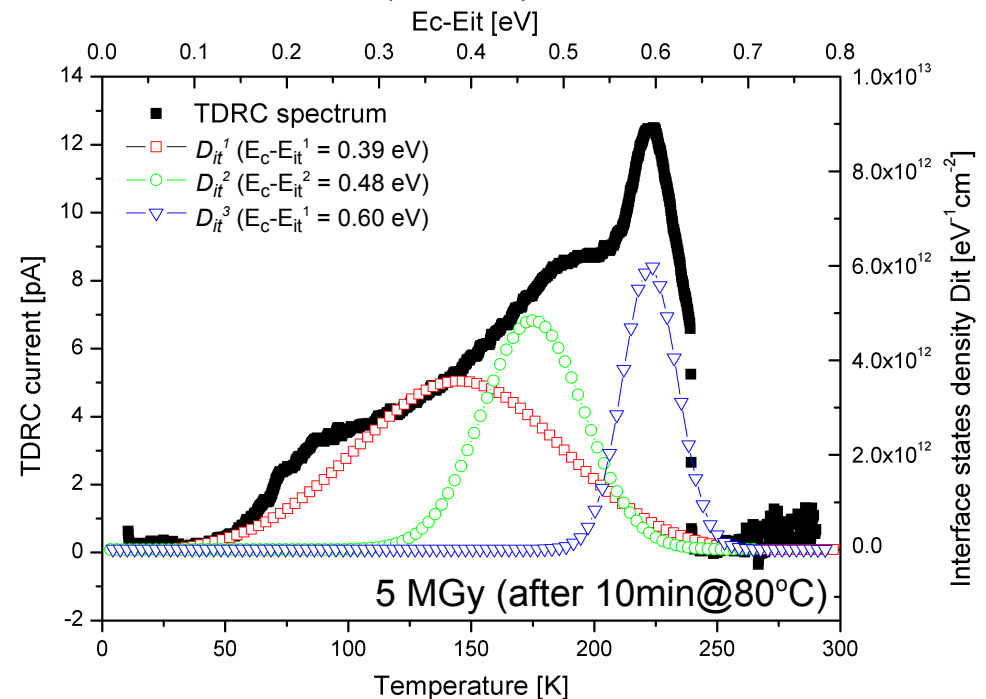
→ fill interface traps with electrons

(2) Cool down to 10 K → freeze traps

(3) Bias to deep depletion and heat up to 290 K → trapped charges at the Si-SiO₂ interface get released

$\left\{ \begin{array}{l} \text{Temperature [K]} \rightarrow E_c - E_{it} \text{ [eV]} \\ \text{TDRC signal [pA]} \rightarrow D_{it} \text{ [eV}^{-1}\text{cm}^{-2}] \end{array} \right.$

$$N_{it}^{(i)} = \int_{E_v}^{E_c} D_{it}^{(i)}(E_{it}) dE_{it}$$



- Properties of 3 dominant interface traps in silicon band gap after X-ray irradiation:

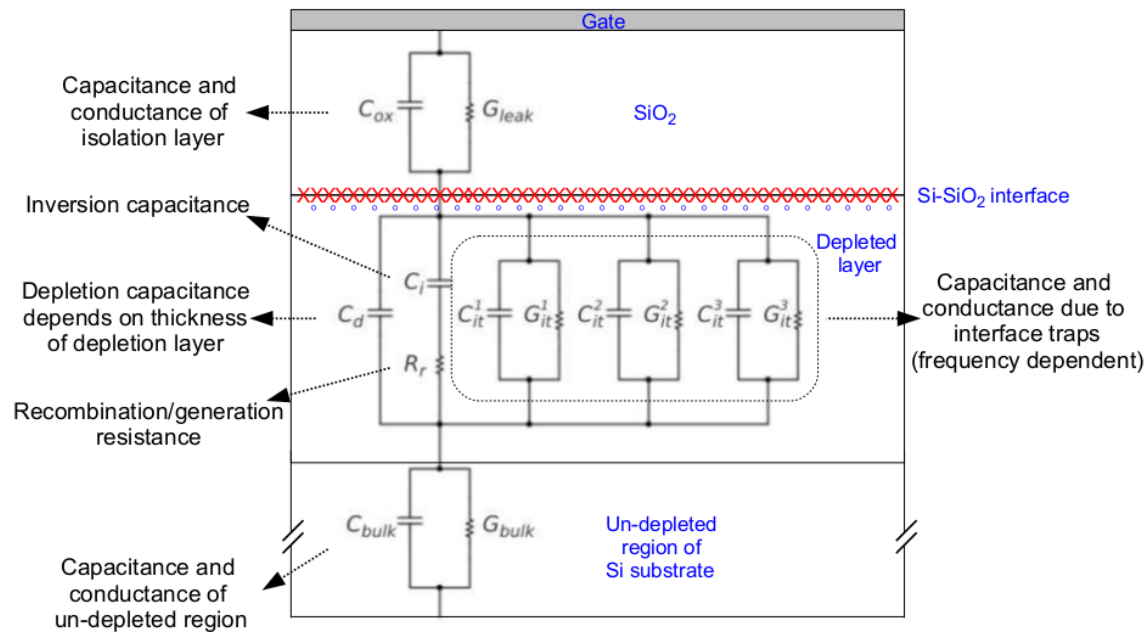
	D_{it}^1	D_{it}^2	D_{it}^3
$E_c - E_{it}$ [eV]	0.39	0.48	0.60
FWHM [eV]	0.26	0.13	0.071
σ_{eff} [cm^2]	1.2×10^{-15}	5.0×10^{-17}	1.0×10^{-15}

Defect characterization: I-V, TDRC & C/G-V

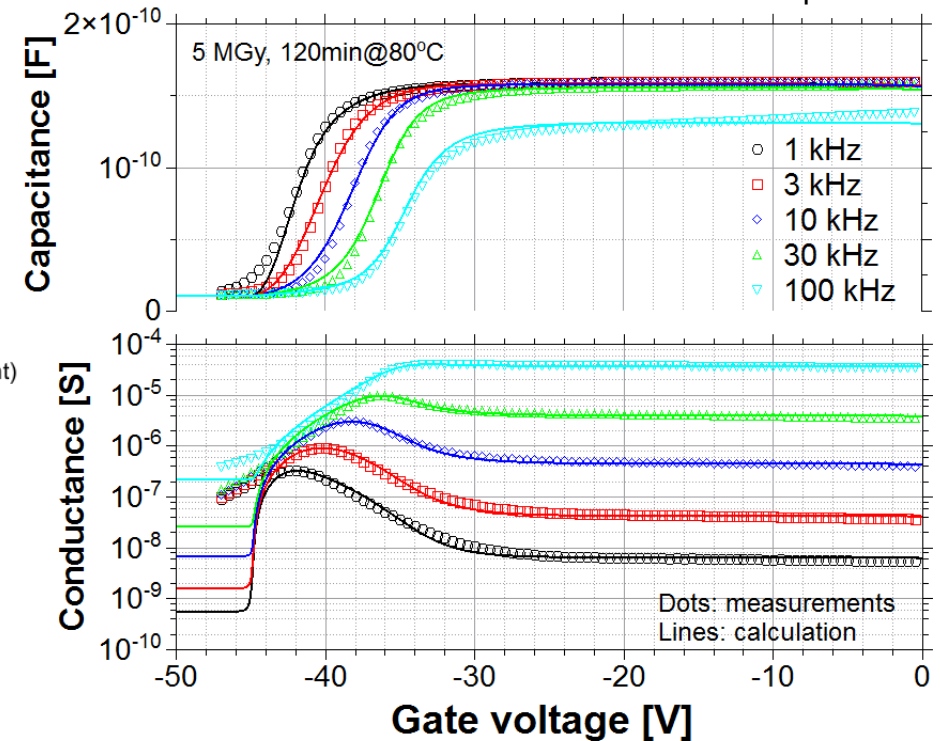
Capacitance/Conductance-Voltage (C/G-V) measurement on MOS capacitor + model calculation for N_{ox} (cm^{-2}):

- Frequency shift of C/G-V curves $\leftarrow N_{it}^{(i)}$
- Shift in gate voltage $\leftarrow N_{ox} + N_{it}^{(i)}$
- TDRC spectra + model \rightarrow reproduce measured C/G-V curves $\rightarrow N_{ox}$

Model for MOS capacitor



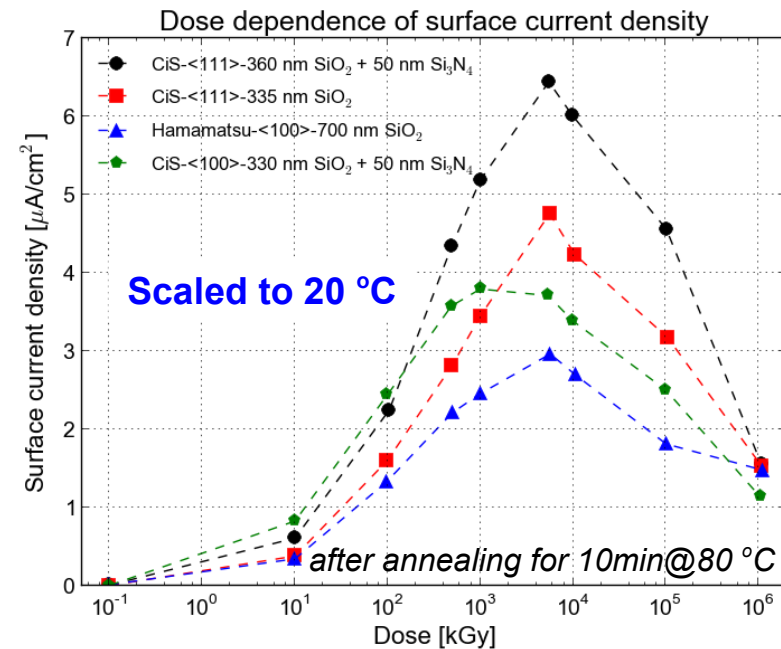
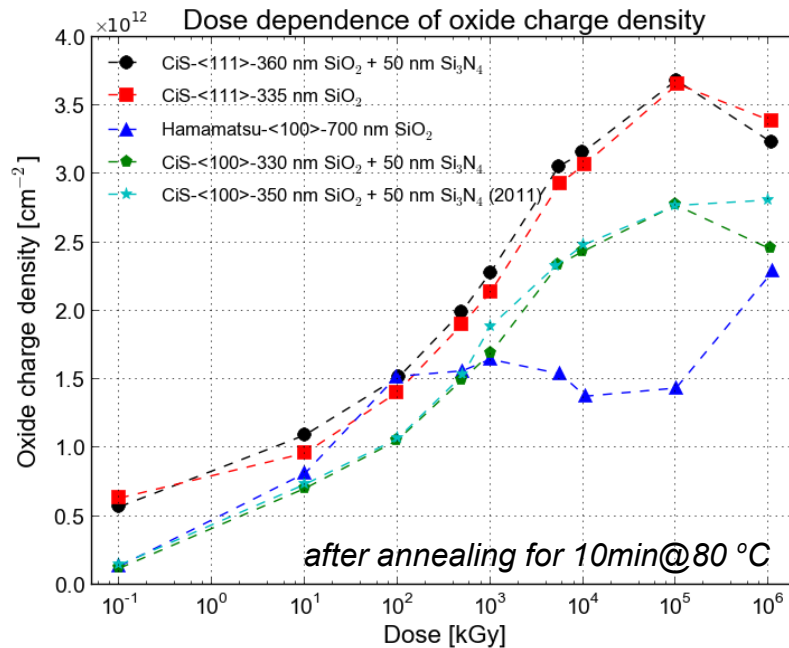
C/G-V measurement on irradiated MOS capacitor



Results: N_{ox} & J_{surf} vs. dose

Investigations:

- Orientation: $\langle 111 \rangle$ and $\langle 100 \rangle$
- Vendor: CiS and Hamamatsu
- Insulator: SiO_2 and $\text{SiO}_2 + \text{Si}_3\text{N}_4$
- Unbiased during irradiation



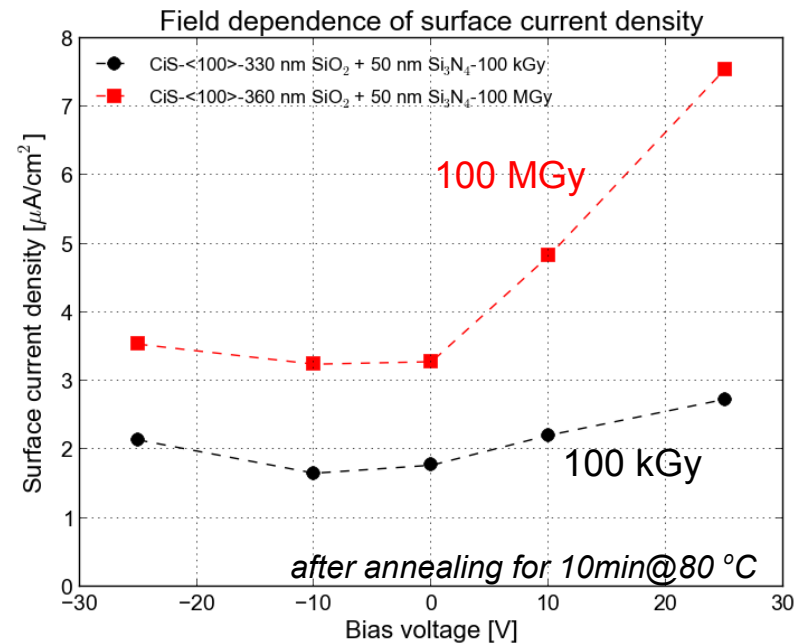
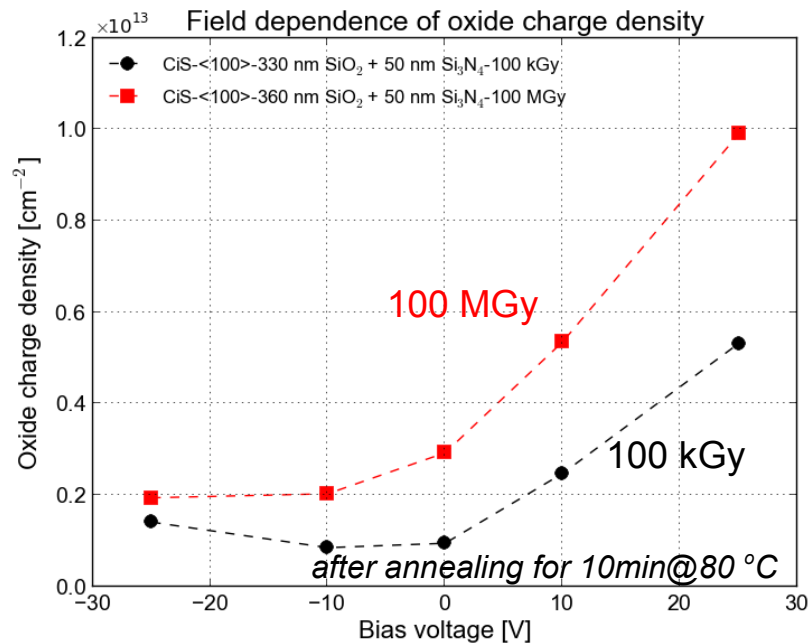
Conclusions:

- N_{ox} and J_{surf} saturate with dose: typically $N_{ox} \sim (1.5 - 4.0) \times 10^{12} \text{ cm}^{-2}$, $J_{surf} \sim (3 - 7) \mu\text{A}/\text{cm}^2$
- Differences observed for orientations, SiO_2 vs. $\text{SiO}_2 + \text{Si}_3\text{N}_4$, vendors
- Saturation mechanism of N_{ox} : equilibrium between hole trapping and electron recombination

Results: N_{ox} & J_{surf} vs. E_{ox}

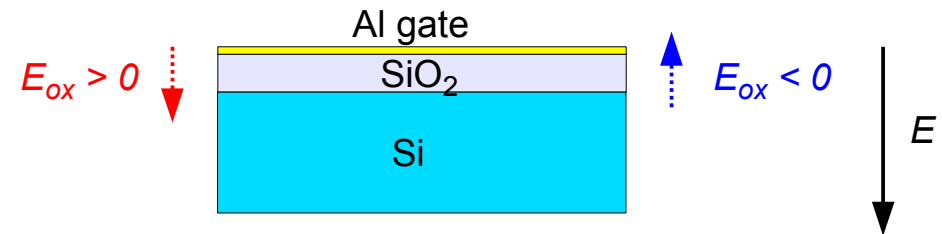
Investigations:

- CiS <100> MOS capacitor and Gate-Controlled Diode (~ 350 nm SiO_2 + 50 nm Si_3N_4)
- Electric field in the oxide E_{ox} : $\sim (0 - 0.7)$ MV/cm [oxide breakdown: ~ 10 MV/cm]



Conclusions:

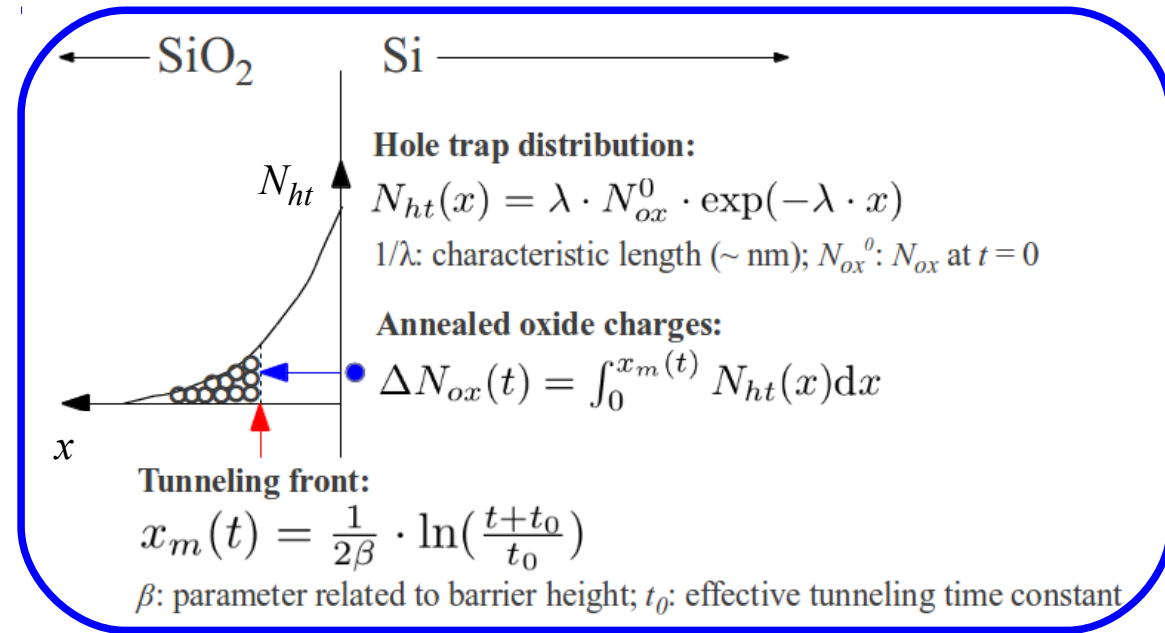
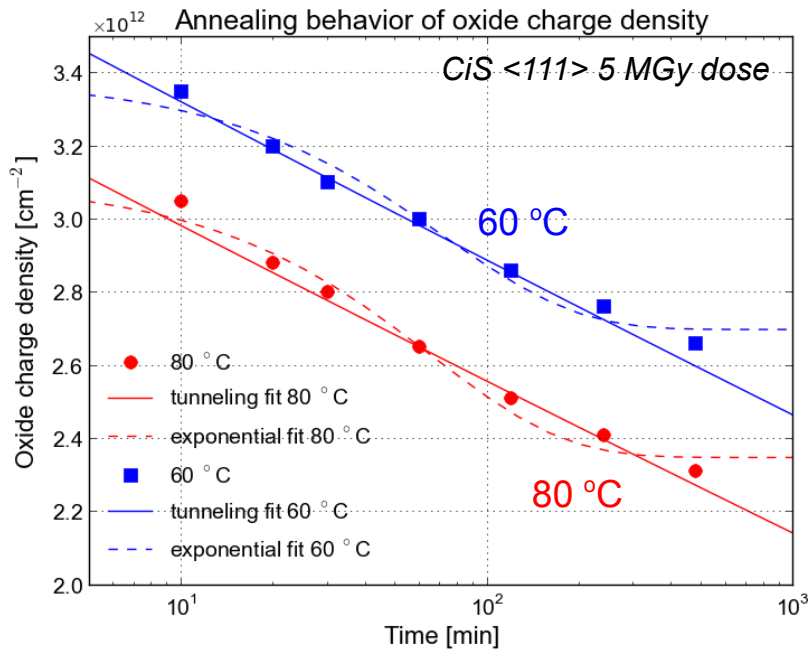
- N_{ox} and J_{surf} increase for $E_{ox} > 0$
- No strong E_{ox} dependence for $E_{ox} < 0$
- p⁺n sensor: $E_{ox} < 0 \rightarrow$ not a problem!



Results of annealing: N_{ox} vs. time

Annealing of N_{ox} :

- Exponential decay: $N_{ox}(t) = A \cdot \exp(-\frac{t}{\tau}) + y_0$ → description inadequate



- “Tunnel anneal” model [T. R. Oldham et al., 1986]:

$$N_{ox}(t) = N_{ox}^0 \cdot (1 + t/t_0)^{-\frac{\lambda}{2\beta}} \quad \text{with} \quad t_0(T) = t_0^* \cdot \exp\left(\frac{\Delta E}{k_B T}\right)$$

t_0^* : tunneling time constant
 ΔE : energy difference between trap level and silicon Fermi level

N_{ox}^0 [cm^{-2}]	$\lambda/2\beta$	t_0^* [s]	ΔE [eV]	T [°C]	80	60	20
3.6×10^{12}	0.070	5.4×10^{-12}	0.91	t_0 [s]	48	290	22000

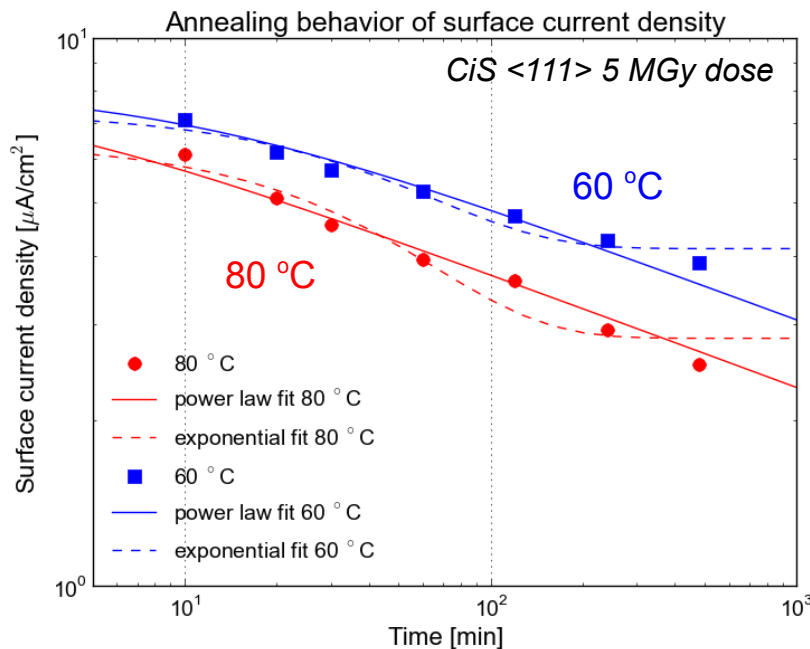
$\Delta E = E_t(\text{SiO}_2) - E_F(\text{Si}) \rightarrow E_t(\text{SiO}_2) \sim 6.0$ eV, compatible with existing data

Results of annealing: J_{surf} vs. time

Annealing of J_{surf} ($I_{surface}$):

- Exponential decay: $I_{surface}(t) = A \cdot \exp(-\frac{t}{\tau}) + y_0$ → description inadequate
- “Two-reaction model”:

$$I_{surface}(t) = I_{surface}^0 \cdot (1 + t/t_1)^{-\eta} \quad \text{with} \quad t_1(T) = t_1^* \cdot \exp\left(\frac{E_\alpha}{k_B T}\right) \quad \text{and} \quad \eta = \frac{k_1}{2k_2}$$



Two-reaction model (M. L. Reed 1987):

→ Dangling bonds: $\frac{d}{dt} [\text{Si}\cdot] = -k_1 [\text{Si}\cdot][\text{H}]$

→ Hydrogen: $\frac{d}{dt} [\text{H}] = -2k_2 [\text{H}][\text{H}]$

k_1 & k_2 : reaction rate

J_{surf}^0 [$\mu\text{A}/\text{cm}^2$]	η	t_1^* [s]	E_α [eV]
8.1	0.21	1.4×10^{-8}	0.70

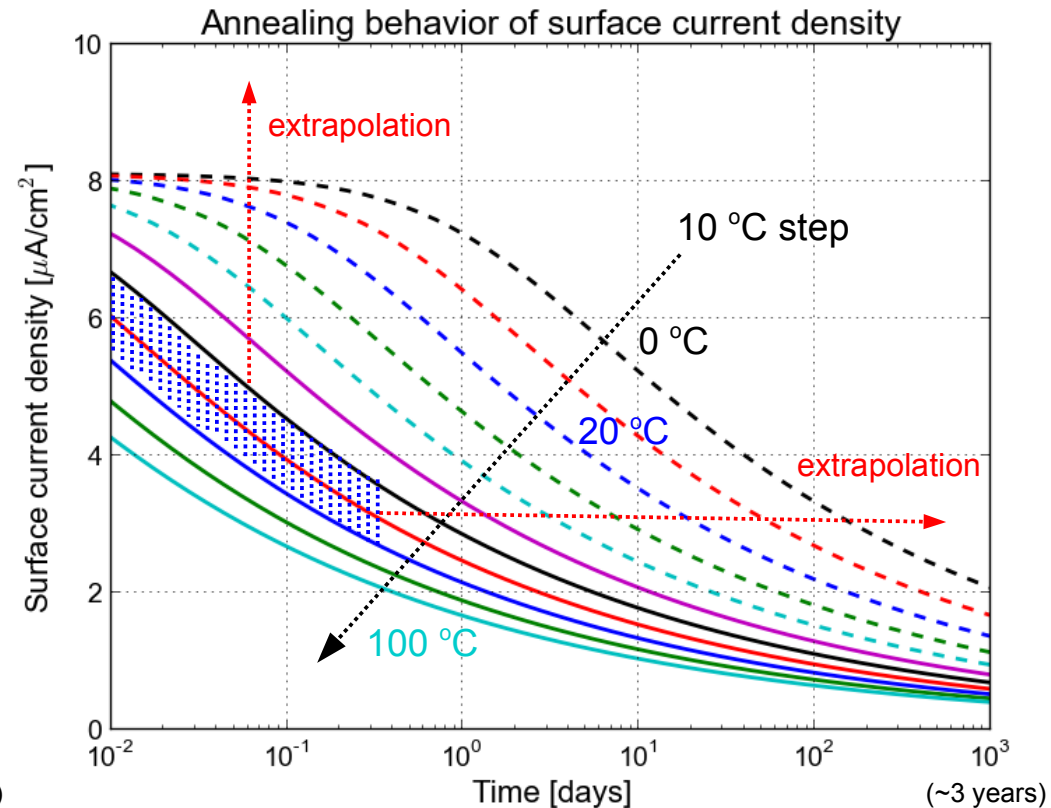
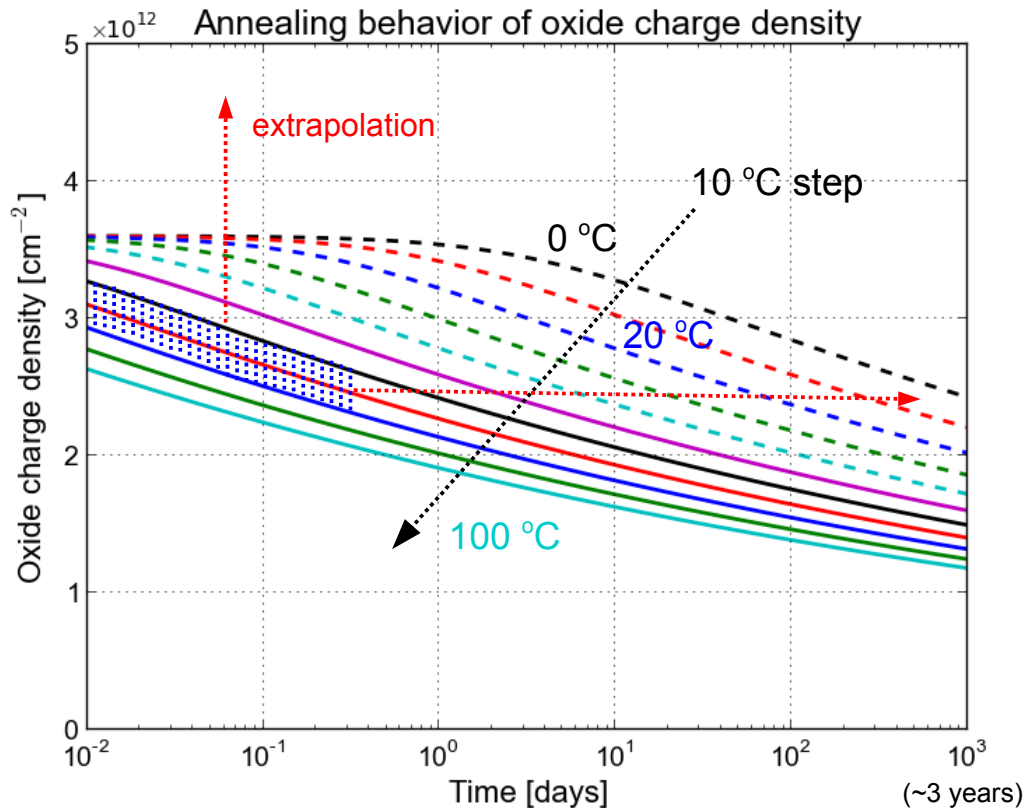
T [°C]	80	60	20
t_1 [s]	140	550	15000

- Data described by power law predicted by “two-reaction model”
- Data show that same function with different parameters for the different traps $N_{it}^{(i)}$ describes data

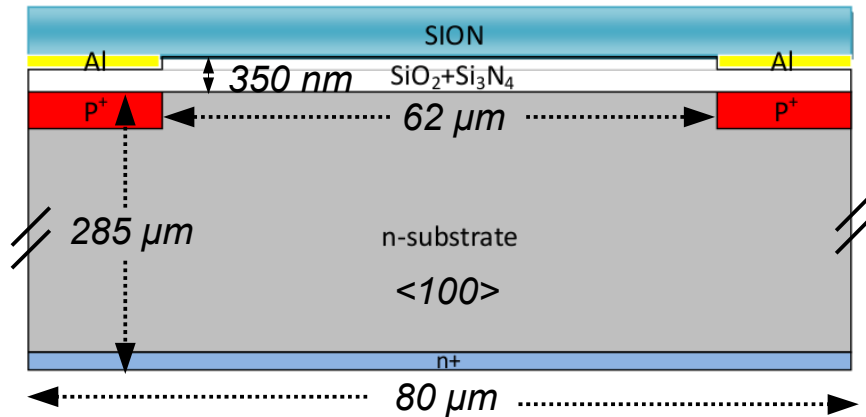
Long term behavior of N_{ox} & J_{surf}

Results based on calculation for 5 MGy dose (results scalable to other doses):

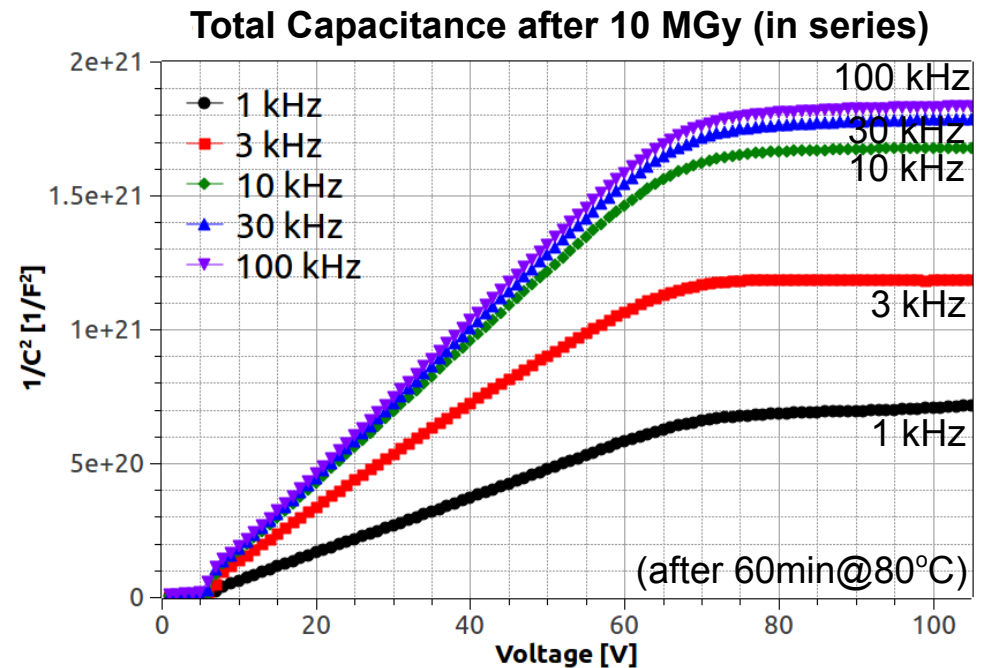
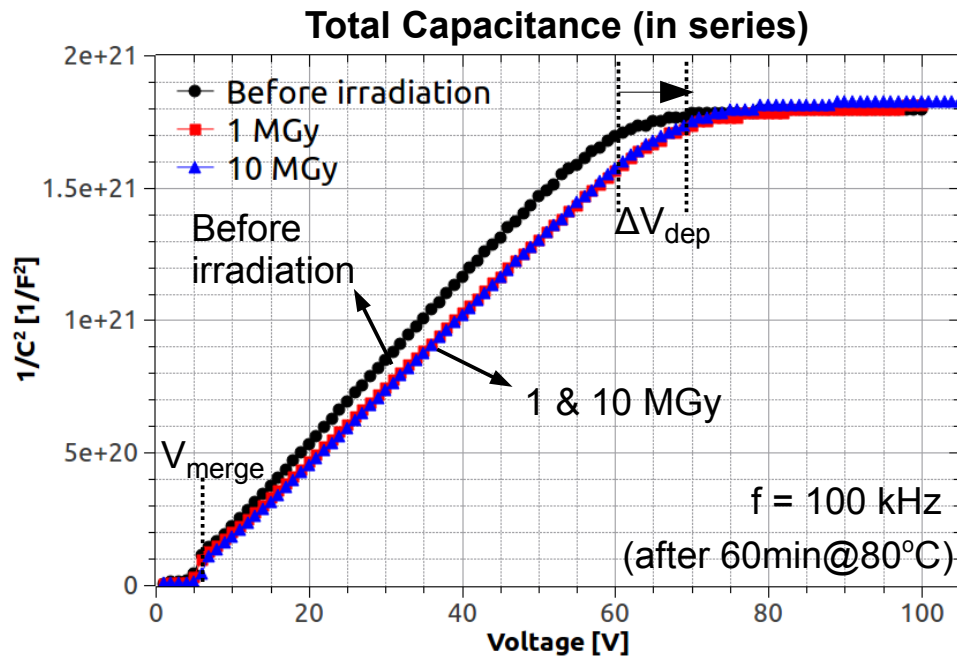
- Slow annealing for N_{ox} : e.g., at 20 °C, $\Delta N_{ox}/N_{ox}$ by less than 50% in 3 years (but...)
- Reduction of J_{surf} in days: e.g., at 20 °C, $\Delta J_{surf}/J_{surf}$ by 50% just in 5 days!



C-V curves of p⁺n strip sensor

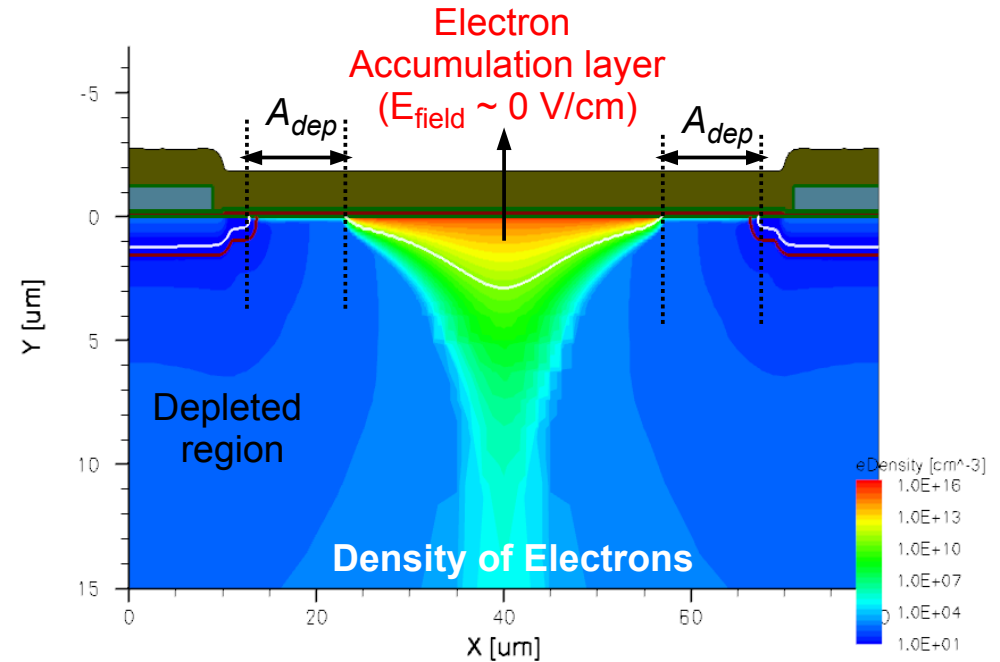
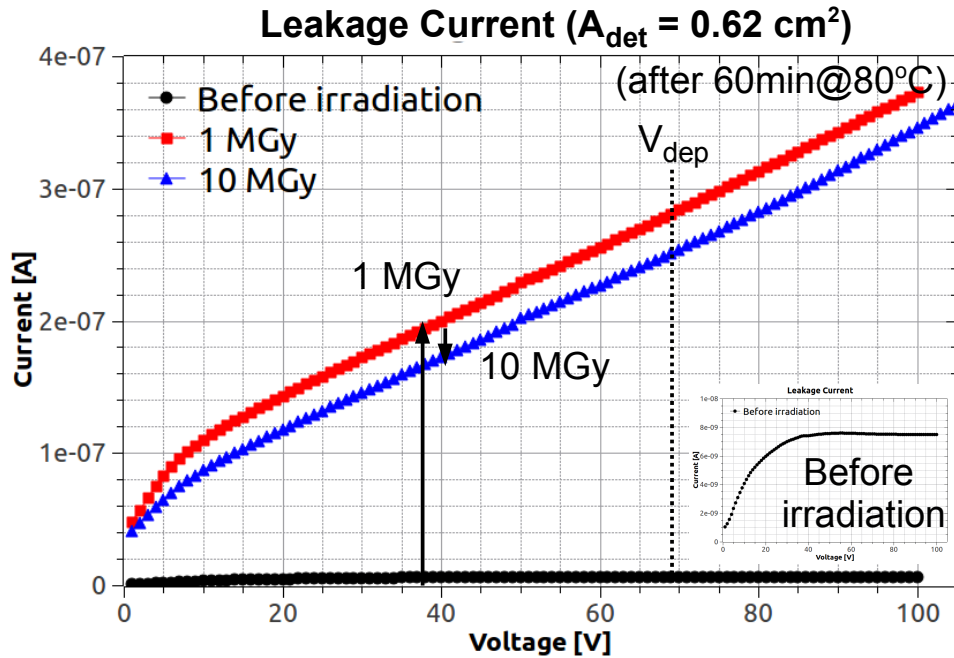


- V_{dep} increases ~ 10 V after irradiation due to the presence of surface charges (not due to change of doping concentration)
- Strong frequency dependence of total capacitance observed for $V_{\text{bias}} < 300$ V



I-V curves of p⁺n strip sensor

- Leakage current: $I_{leakage} = I_{bulk} + I_{surface}$, where $I_{surface} = J_{surf} \cdot A_{dep}$



- Increase of $I_{leakage}$ after irradiation \leftarrow surface current density $J_{surf} \leftarrow N_{it}$
- “Linear” increase of $I_{leakage}$ with bias voltage \leftarrow depleted area A_{dep} at Si-SiO₂ interface
- Decrease of $I_{leakage}$ with irradiation dose \leftarrow result of competition between N_{it} and A_{dep}
- For irradiation under bias, $I_{leakage}$ larger by $\sim 100 \text{ nA}$

Review on other achievements

Other work done and experiences:

- Dose calibration and operation of irradiation setup at the DESY DORIS III synchrotron light source
- Helped colleagues from other labs with irradiation set-up
- Model development for irradiated MOS capacitors
- SPICE simulation for non-irradiated p^+ on n microstrip sensors
- Test beam experiment at CERN SPS with T. Rohe, J. Sibille, et al.
- Response of PMOSFET and NMOSFET to irradiation dose
- Characterization of electrical properties of n^+ on n pixel sensors with X-ray irradiation
- Mask design of the AGIPD sensor for the European XFEL
- Supervision of a summer student from National Technical University of Athens

Review on other achievements

Talks given:

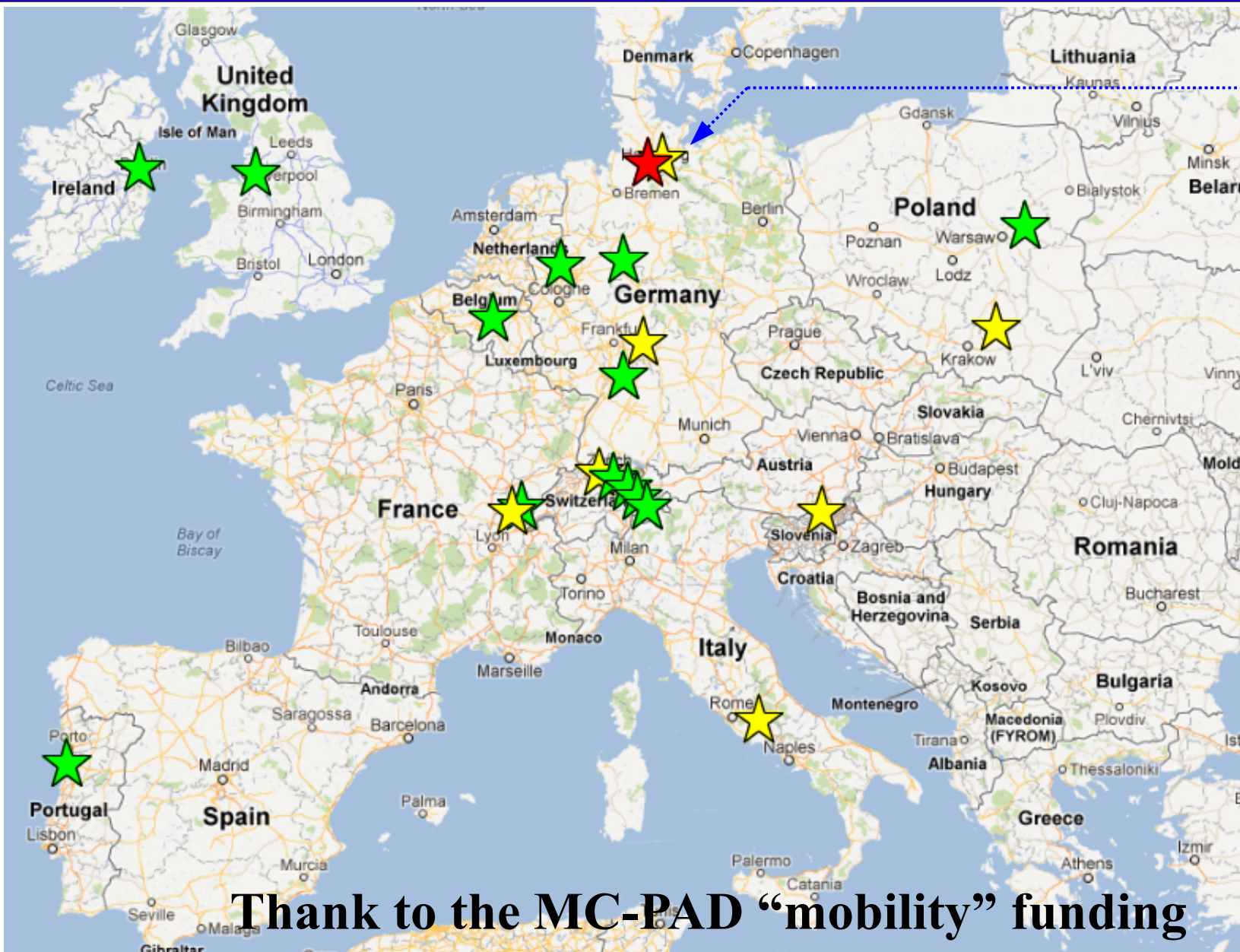
- “Investigation of X-ray induced radiation damage at the Si-SiO₂ interface of silicon pixel sensors for the European XFEL” at 14th iWoRID, July 2012, Figueira da Foz, Coimbra, Portugal
- “Status report: Radiation damage and sensors” at 10th XDAC Meeting, October 2011, XFEL GmbH-Hamburg
- “Study of X-ray radiation damage in silicon sensors” at 13th iWoRID, July 2011, ETH-Zurich and PSI-Villingen
- “Study of surface radiation damage in silicon sensors” at 18th RD50 Workshop, May 2011, Liverpool

Review on other achievements

Work results in:

- **J. Zhang**, et al., “Investigation of X-ray induced radiation damage at the Si-SiO₂ interface of silicon pixel sensors for the European XFEL”, to be published by *Journal of Instrumentation*.
- T. Poehlsen, et al., “Charge losses in segmented silicon sensors at the Si-SiO₂ interface”, to be published by *Nuclear of Instruments and Methods A*.
- **J. Zhang**, et al., “Study of radiation damage induced by 12 keV X-rays in MOS structures built on high resistivity n-type silicon”, *Journal of Synchrotron Radiation*, Vol.19, Issue 3, 340-346 (2012).
- J. Schwandt, et al., “Optimization of the radiation hardness of silicon pixel sensors for high X-ray doses using TCAD simulations”, *Journal of Instrumentation*, Vol.7, C01006 (2012).
- **J. Zhang**, et al., “Study of X-ray radiation damage in silicon sensors”, *Journal of Instrumentation*, Vol.6, C11013 (2011).

Benefits from MC-PAD framework



★
Currently, I am in Hamburg writing and finalizing the PhD thesis.

★
Future: Postdoc

★
MC-PAD training

★
Conferences, meetings and workshops

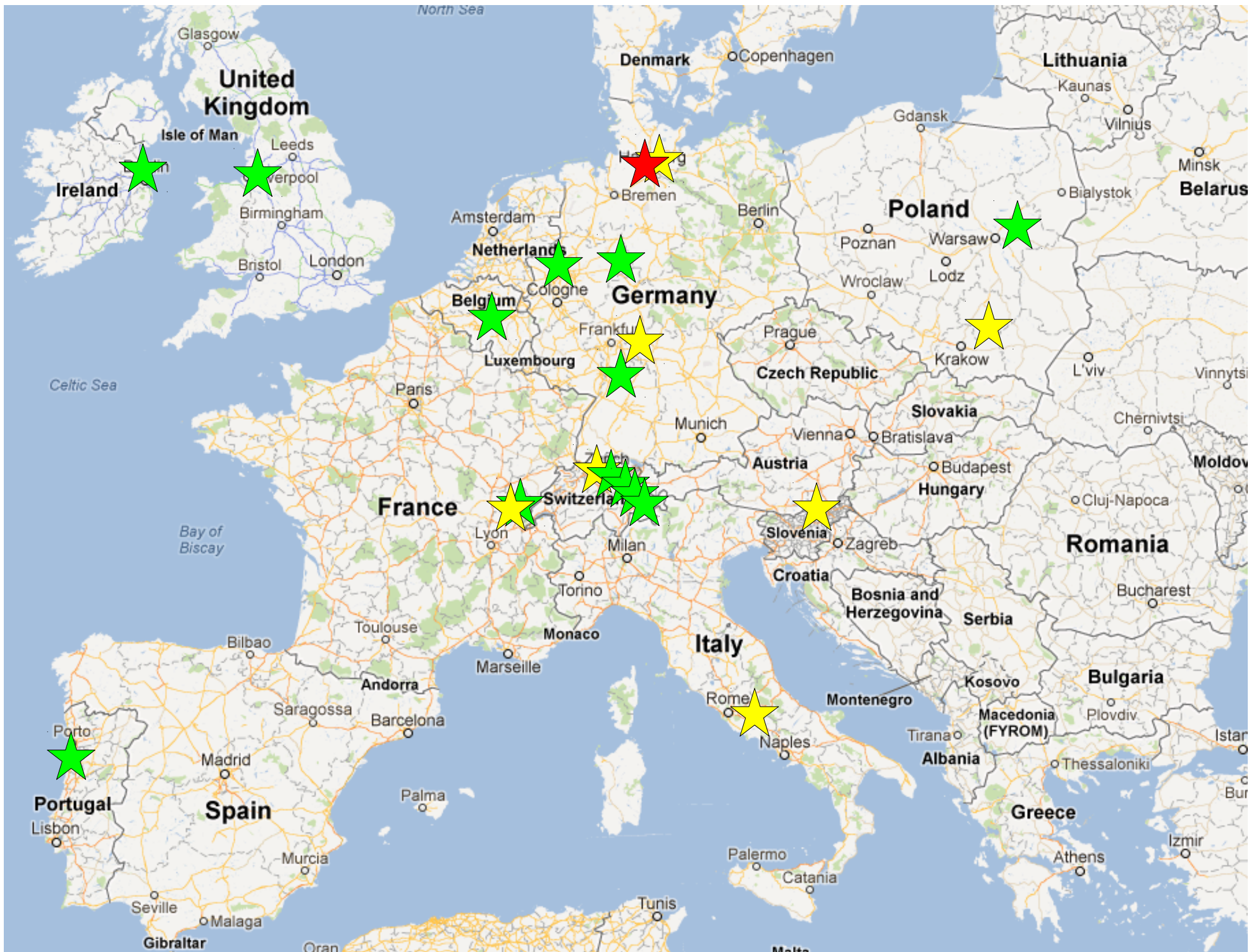
Suggestion:
Exchange between researchers from different institutes

Thank to the MC-PAD “mobility” funding

Special thanks go to:

- MC-PAD program
- Christian Joram
- All fellows within the MC-PAD
- Prof. Robert Klanner
- All those I worked with: Eckhart Fretwurst, Ioana Pintilie, Tilman Rohe, Joern Schwandt, Monica Turcato, Thomas Poehlsen, Jennifer Sibille, Thorben Theedt, Hanno Perrey, ...

***Thanks for your attention,
and good luck for your future!***



Results: N_{it} vs. E_{ox}

TDRC spectra and N_{it} :

- Dependence on E_{ox} similar to J_{surf}
- TDRC spectra:
 100 kGy \rightarrow change of amplitude
 100 MGy \rightarrow change of shape and amplitude

